IN THE CLAIMS

Claims 1-9 (Cancelled)

10.   (Original) An apparatus, comprising:
       means for positioning a substrate near an embossing foil; and
       means for checking a drift of the substrate relative to the embossing foil.

11.   (Original) The apparatus of claim 10, wherein means for positioning further comprises means for centering the substrate relative to the embossing foil.

12.   (Original) The apparatus of claim 10, wherein means for checking further comprises means for repositioning the substrate relative to the embossing foil.

13.   (Original) The apparatus of claim 10, wherein means for positioning further comprises means for maintaining a pre-heated temperature of an embossable film disposed above the substrate.

14.   (Original) An apparatus, comprising:
       an embossing foil;
       a nest disposed below the embossing foil, the nest having an gas-bearing surface to receive a substrate having an outer dimension; and
       a plurality of piezo actuators disposed near the gas-bearing nest, the plurality of piezo actuators to engage the outer dimension to center the substrate relative to the embossing foil.

15.   (Original) The apparatus of claim 14, further comprising a controller coupled to the plurality of piezo actuators to sense a motion stoppage of the substrate.

16.   (Original) The apparatus of claim 14, wherein the plurality of piezo actuators comprise a push rod to engage the outer dimension of the substrate.

17. (Original) The apparatus of claim 14, wherein the plurality of piezo actuators comprise nano actuators.

18. (Original) The apparatus of claim 14, further comprising an actuator control algorithm to control the plurality of piezo actuators while engaged with the outer dimension.

19. (Original) The apparatus of claim 14, wherein the nest is defined by a wall, and wherein the gas-bearing surface prevents the substrate from making mechanical contact with the nest.

20. (Original) The apparatus of claim 14, wherein the substrate comprises a disk having an outer diameter to engage the plurality of piezo actuators.